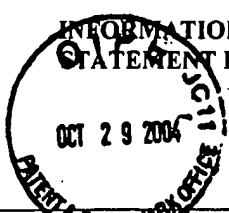


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Examiner Initials	<i>AR</i>	Date Considered	01/23/05
EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.			